

ABSTRACT

A work attracting apparatus and a work attracting method that uses a Bernoulli chuck or the like as a work attraction section and that can ensure the perfect operation of attracting and receiving. The work attraction section (Bernoulli plate 1 and Bernoulli arm 2) attracts a wafer 14 being transported in; a movement section (moving unit 3 and speed variable actuator 10) moves the work attraction section in a direction of transport of the wafer 14; a work detector 4 detects the wafer 14 being transported at a predetermined position and outputs a detection signal; and a controller 5, when receiving the detection signal, controls the movement section to move together with the wafer 14 being transported and makes the work attraction section operate.